

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Masahiko NAKAMORI, et al.
Appl. No. : 10/536,621
Filed : May 26, 2005
For : POLISHING PAD AND METHOD
OF PRODUCING
SEMICONDUCTOR DEVICE
Examiner : Sylvia McCarthur
Group Art Unit : 1792

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Katsuhiro Arai, Reg 43,315AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed December 10, 2007, please reconsider the present application in light of the following amendments and comments.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.